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a reflective element directly below the shielding layer, wherein the shielding layer is thinner than the reflective element.

2. The image sensor device as claimed in claim 1, wherein a bottom of the shielding layer is substantially coplanar with a bottom of the filter.

3. The image sensor device as claimed in claim 1, wherein the shielding layer comprises a metal material.

4. The image sensor device as claimed in claim 1, further comprising a lens over the photodetector.

5. The image sensor device as claimed in claim 1, further comprising an anti-reflection layer between the semiconductor substrate and the shielding layer.

6. The image sensor device as claimed in claim 1, further comprising:

a second dielectric layer surrounding the reflective element, wherein the second dielectric layer is between the semiconductor substrate and the dielectric layer.

7. The image sensor device as claimed in claim 6, wherein materials of the reflective element and the shielding layer are the same.

8. The image sensor device as claimed in claim 6, further comprising:

a black level correction region in the semiconductor substrate; and

a shielding element over the black level correction region, wherein materials of the shielding element and the reflective element are the same.

9. An image sensor device, comprising:

a semiconductor substrate having a first pixel region and a second pixel region;

a first photodetector and a second photodetector in the first pixel region and the second pixel region, respectively;

a dielectric layer over the semiconductor substrate, wherein the dielectric layer has a first recess and a second recess aligned with the first photodetector and the second photodetector, respectively;

a first filter and a second filter in the first recess and the second recess, respectively, wherein the first filter has a protruding portion protruding from a bottom surface of the dielectric layer;

a shielding layer between the dielectric layer and the semiconductor substrate and surrounding the first filter and the second filter, wherein the first filter and the shielding layer overlap from a view facing a direction perpendicular to a normal direction of a top surface of the semiconductor substrate, and the shielding layer surrounds the protruding portion of the first filter; and

a reflective element directly below the shielding layer, wherein the shielding layer is thinner than the reflective element.

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10. The image sensor device as claimed in claim 9, wherein the second filter has a second protruding portion protruding from a bottom surface of the dielectric layer, and the shielding layer surrounds the second protruding portion of the second filter.

11. The image sensor device as claimed in claim 9, wherein a bottom of the shielding layer is substantially coplanar with bottoms of the first filter and the second filter.

12. The image sensor device as claimed in claim 9, wherein the shielding layer comprises a metal material, a polymer material, a semiconductor material, a ceramic material, or a combination thereof.

13. The image sensor device as claimed in claim 9, wherein a thickness of the shielding layer is in a range from about 10 nm to about 500 nm.

14. An image sensor device, comprising:

a semiconductor substrate;

a photodetector in the semiconductor substrate;

a filter over the semiconductor substrate and aligned with the photodetector;

a dielectric layer over the semiconductor substrate and surrounding the filter;

a shielding layer over the semiconductor substrate and surrounding a lower portion of the filter, wherein the lower portion of the filter protrudes from a bottom surface of the dielectric layer, and the shielding layer and the lower portion of the filter overlap from a view facing a direction perpendicular to a normal direction of a top surface of the semiconductor substrate; and

a reflective element directly below the shielding layer, wherein the shielding layer is thinner than the reflective element.

15. The image sensor device as claimed in claim 14, wherein bottoms of the shielding layer and the filter are substantially coplanar with each other.

16. The image sensor device as claimed in claim 14, wherein the shielding layer comprises a metal material.

17. The image sensor device as claimed in claim 14, further comprising:

a second dielectric layer surrounding the reflective element, wherein the second dielectric layer is between the semiconductor substrate and the filter.

18. The image sensor device as claimed in claim 17, wherein materials of the shielding layer and the reflective element are substantially the same.

19. The image device as claimed in claim 1, wherein the reflective element is separated from the shielding layer.

20. The image device as claimed in claim 1, wherein the shielding layer is wider than the reflective element.

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